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	Applicant(s): Mitsushi FUJIKI	
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U.S. PATENT DOCUMENTS

Examiner Initial	Document No.	Name	Date	Class	Subclass	Filing Date (If appropriate)
	AA					
	AB					
	AC					
	AD					

FOREIGN PATENT DOCUMENTS

Document No.	Date	Country	Translation (Yes or No)		
wp	AE	9-53188	02/25/97	Japan	Abstract & Discussed in the Spec.
	AF				
	AG				
	AH				
	AI				

OTHER DOCUMENTS

wp	AJ	Jpn. J. Appl. Phys. Vol. 36 (1997) pp. L154-L157, Part 2, No. 2A, 1 February 1997
	AK	Takeshi OHWAKI et al., Preferred Orientation in Ti Films Sputter-Deposited on SiO2 Glass: The Role of Water Chemisorption on the Substrate
Examiner	pham mark	
Date Considered	6/24/2005	